



Liquid Chemicals Global Technical Committee Japan TC Chapter

Meeting Summary and Minutes

December 3, 2021

10:00 – 12:00

OVTCCM

TC Chapter Announcements

Next TC Chapter Meeting

May 27th, 10:00-12:00

SEMI Japan office, Tokyo / OCTCCM (Hybrid)

Table 1 Meeting Attendees

Italics indicate virtual participants

Co-Chairs: *Hiroshi Tomita (KIOXIA), Yoshiyuki Fujitani (SCREEN Semiconductor Solutions),*

Hiroyuki Araki (SCREEN Semiconductor Solutions)

SEMI Staff: Keigo Nakajima

<i>Company</i>	<i>Last</i>	<i>First</i>	<i>Company</i>	<i>Last</i>	<i>First</i>
<i>KIOXIA</i>	<i>Tomita</i>	<i>Hiroshi</i>	<i>Nihon Pall</i>	<i>Takakura</i>	<i>Tomoyuki</i>
<i>Organo</i>	<i>Sugawara</i>	<i>Hiroshi</i>	<i>X-FAB Sarawak Sdn. Bhd</i>	<i>Liew</i>	<i>Emily</i>
<i>SCREEN Semiconductor Solutions</i>	<i>Fujitani</i>	<i>Yoshiyuki</i>	<i>Nihon Entegris</i>	<i>Nagafuchi</i>	<i>Takuya</i>
<i>AIST</i>	<i>Kato</i>	<i>Haruhisa</i>	<i>Nihon Pall</i>	<i>Tsuzuki</i>	<i>Shuichi</i>
<i>RION</i>	<i>Kondo</i>	<i>Kaoru</i>	<i>Advance Electric</i>	<i>Sasao</i>	<i>Kimihito</i>
<i>SCREEN Semiconductor Solutions</i>	<i>Araki</i>	<i>Hiroyuki</i>	<i>SEMI Japan</i>	<i>Nakajima</i>	<i>Keigo</i>

Table 2 Leadership Changes

<i>WG/TF/SC/TC Name</i>	<i>Previous Leader</i>	<i>New Leader</i>
Japan TC Chapter of Liquid Chemicals Global Technical Committee	Hiroshi Tomita / KIOXIA Hiroyuki Araki / SCREEN Semiconductor Solutions Fujitani Yoshiyuki / SCREEN Semiconductor Solutions	Hiroshi Tomita / KIOXIA Fujitani Yoshiyuki / SCREEN Semiconductor Solutions

Table 3 Committee Structure Changes

None

Table 4 Ballot Results

None

Table 5 Activities Approved by the GCS between meetings of the TC Chapter

None

Table 6 Authorized Activities

Listing of all revised or new SNARF(s) approved by the Originating TC Chapter.

#	Type	SC/TF/WG	Details
6820	SNARF	Trace Metal Analysis for High Pure IPA TF	New Standard: Guide for Trace Iron Analysis in High Purity IPA

#1 SNARFs and TFOFs are available for review on the SEMI Web site at:

<http://downloads.semi.org/web/wstdsbal.nsf/TFOFSNARF>

Table 7 Authorized Ballots

None

Table 8 SNARF(s) Granted a One-Year Extension

None

Table 9 SNARF(s) Abolished

Table 10 Standard(s) to receive Inactive Status

None

Table 11 New Action Items

None

Table 12 Previous Meeting Action Items

None

1 Welcome, Reminders, and Introductions

Hiroyuki Araki (SCREEN Semiconductor Solutions) called the meeting to order at 10:00. The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed. Attendees introduced themselves.

Attachment: 1_RequiredElementNov2020Rev1-E&J-r1

2 Review of Previous Meeting Minutes

The TC Chapter reviewed the minutes of the previous meeting.

Motion: Approve the minutes as written

By / 2nd: Takuya Nagafuchi / Nihon Entegris K.K., Tomoyuki Takakura / Nihon Pall Ltd.

Discussion: First name of Hiroshi Sugawara should be fixed.

Vote: 9:0 Pass

Attachment: 2-01_Mins_0618v1.1, 2-02_Mins_0618v1.2,

3 Liaison Reports

3.1 *Liquid Chemicals North America TC Chapter*

Keigo Nakajima (SEMI) reported for the NA TC Chapter.

Attachment: 3-01_NA LChem Liaison Report Oct2021 v1

3.2 *SEMI Staff Report*

Keigo Nakajima (SEMI) gave the SEMI Staff Report.

Attachment: 3-02_Staff Report October 2021 v1

4 Ballot Review

None

5 Subcommittee and Task Force Reports

5.1 *Liquid Filter TF*

Tomoyuki Takakura (Nihon Pall) reported for the Task Force.

TF is continuing to discuss for the new test method.

5.2 *Liquid-Borne Particle Counter TF*

Kaoru Kondo (Rion) reported that there is no action at the moment but preparing for next year's 5-year review.

5.3 *Diaphragm Valve TF* - No Report

5.4 *Welding Fitting TF* - No Report

5.5 *Trace Metal Analysis for High Pure IPA TF*

Hiroshi Sugawara (Organo) reported for the Task Force. TF is planning to submit the new SNARF for New Standard: GUIDE FOR TRACE IRON ANALYSIS IN HIGH PURITY 2-PROPANOL (IPA)

6 Old Business

6.1 5-year Review

Due to the 5 years period, Keigo Nakajima (SEMI) explained and asked to approve the SNARF (Reapproval of SEMI C89).

Motion: Reapproval of SEMI C89 - Test Method for Particle Removal Performance of Liquid Filter Rated Below 30 nm with Inductively Coupled Plasma – Mass Spectroscopy (ICP-MS)

By / 2nd: Takuya Nagafuchi / Nihon Entegris K.K., Tomoyuki Takakura / Nihon Pall Ltd.

Discussion: None

Vote: 9:0 Pass

Attachment: 6_C89_SNARF_Oct2021 (reapproval)

7 New Business

7.1 Yoshiyuki Fujitani (SCREEN Semiconductor Solutions) reported that Hiroyuki Araki (SCREEN Semiconductor Solutions) will step down from the co-chair Japan TC Chapter of Liquid Chemicals Global Technical Committee.

8 Next Meeting and Adjournment

The next meeting is scheduled for May 27th 10:00-12:00 at SEMI Japan office, Tokyo / OCTCCM (Hybrid)

See <http://www.semi.org/standards-events> for the current list of events.



Adjournment: 12:00.

Respectfully submitted by:

Keigo Nakajima

SEMI Japan

Phone: 81.3332.5863

Email: knakajima@semi.org

Minutes tentatively approved by:

Hiroshi Tomita (KIOXIA), Co-chair	December 16, 2021
Yoshiyuki Fujitani (SCREEN Semiconductor Solutions), Co-chair	December 16, 2021

Table 13 Index of Available Attachments^{#1}

<i>Title</i>	<i>Title</i>
1_RequiredElementNov2020Rev1-E&J-r1	2-01_Mins_0618v1.1
2-02_Mins_0618v1.2	3-01_NA LChem Liaison Report Oct2021 v1
3-02_Staff Report October 2021 v1	6_C89_SNARF_Oct2021 (reapproval)

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact [SEMI Staff Name] at the contact information above.